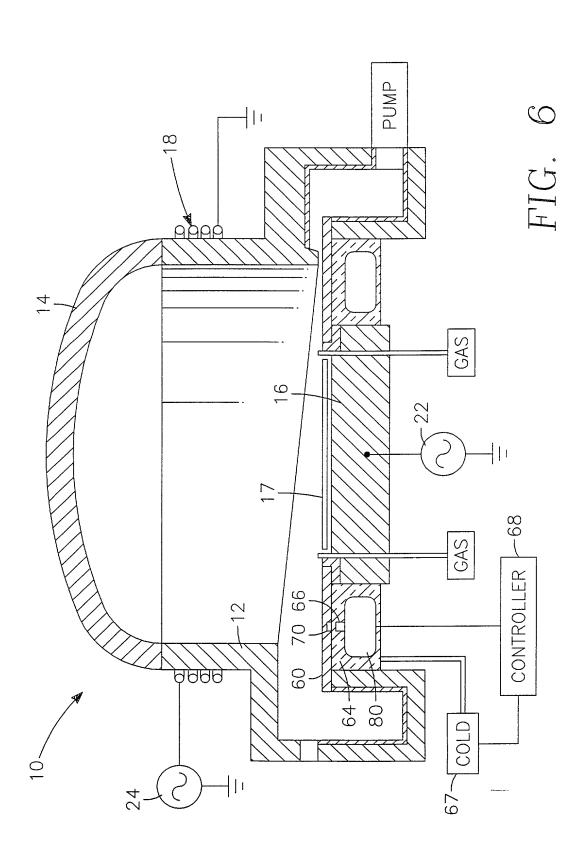
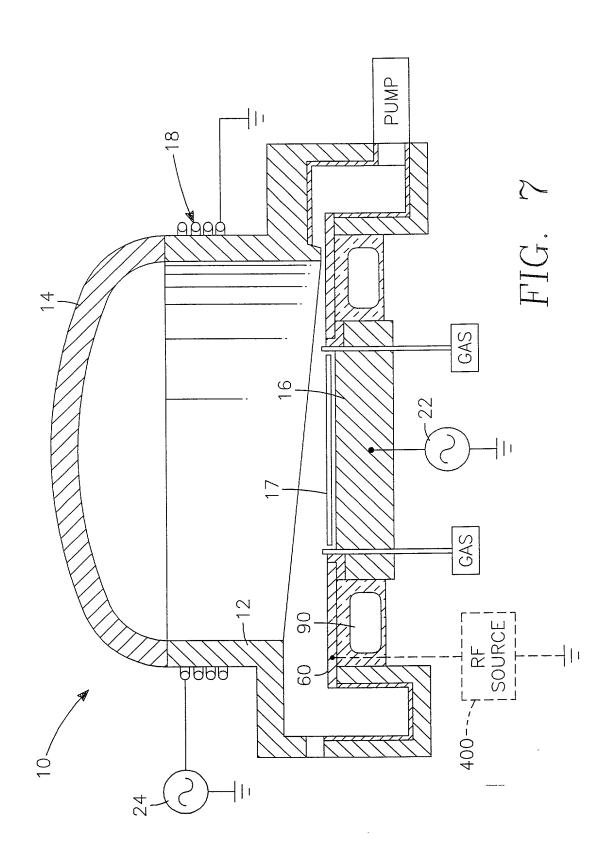
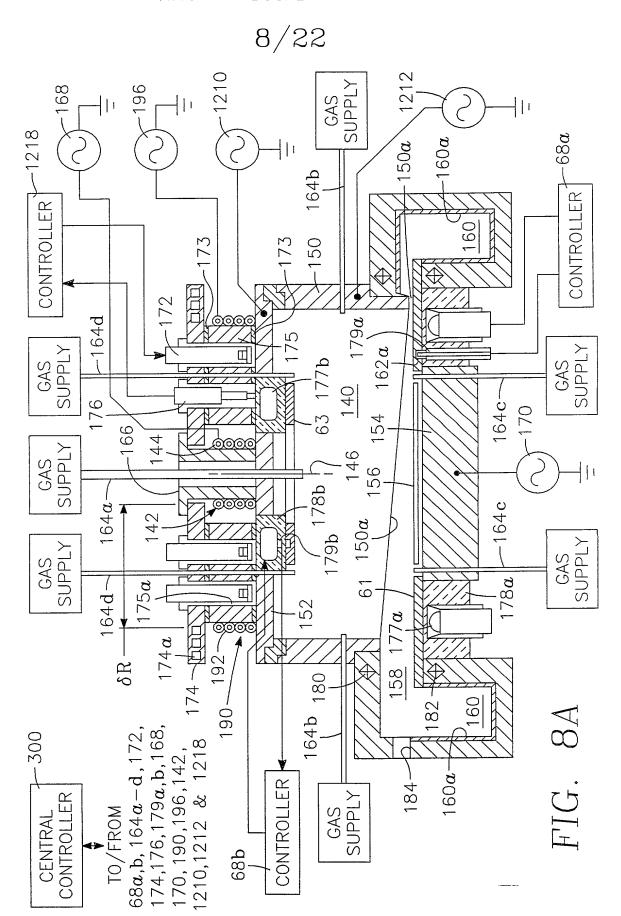
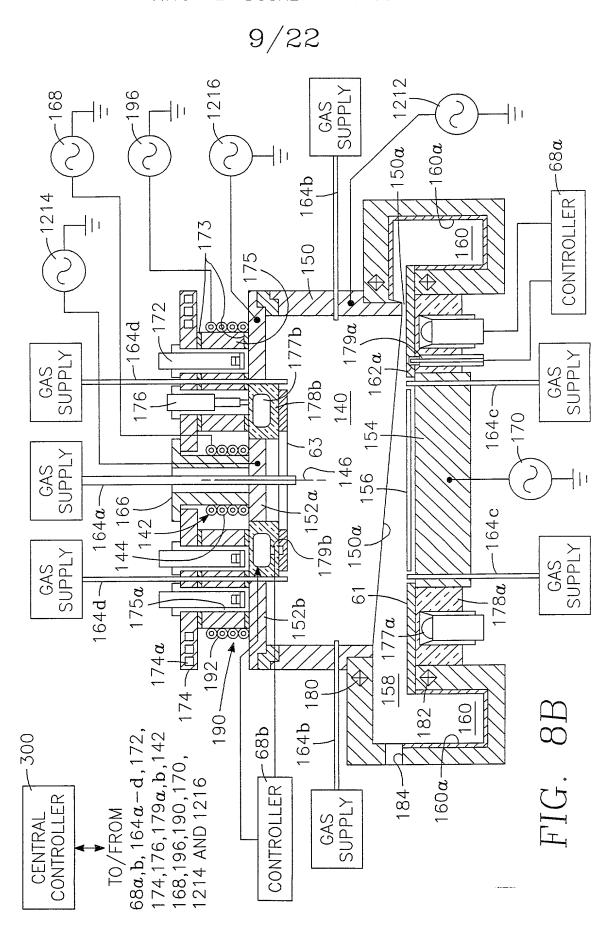


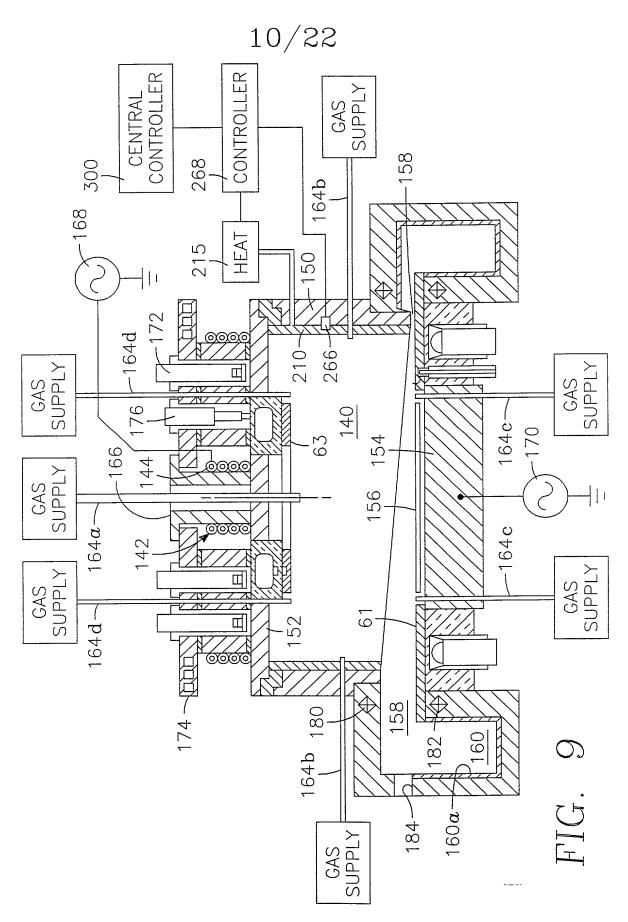
FIG. 5B

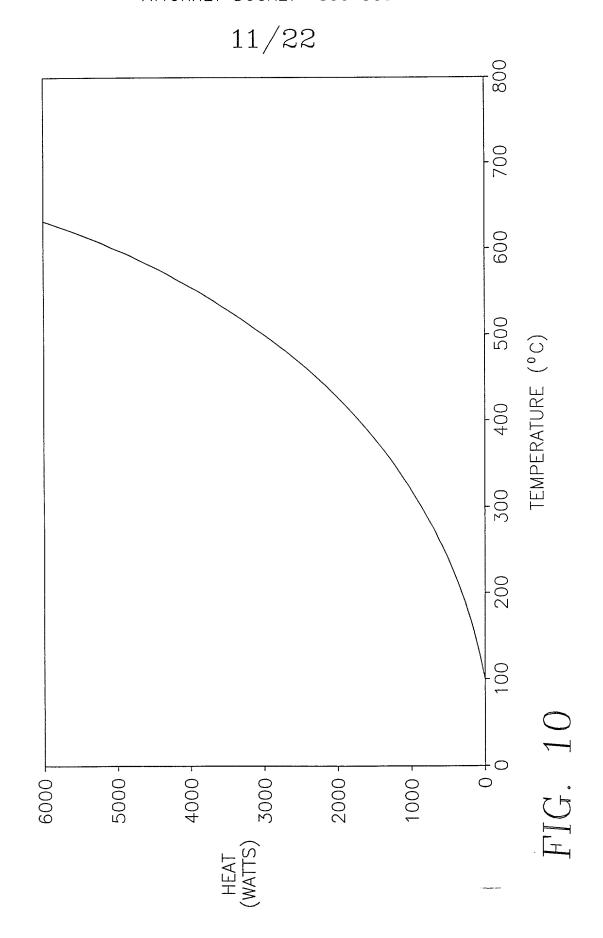




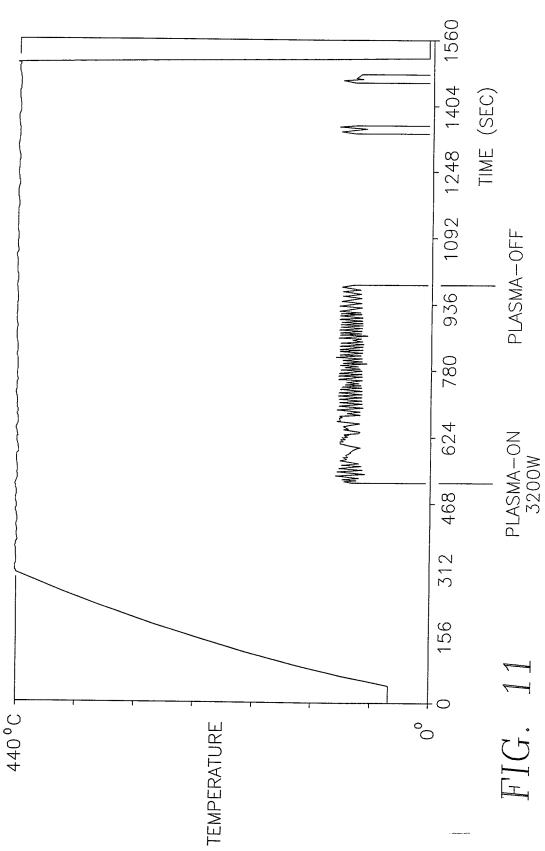




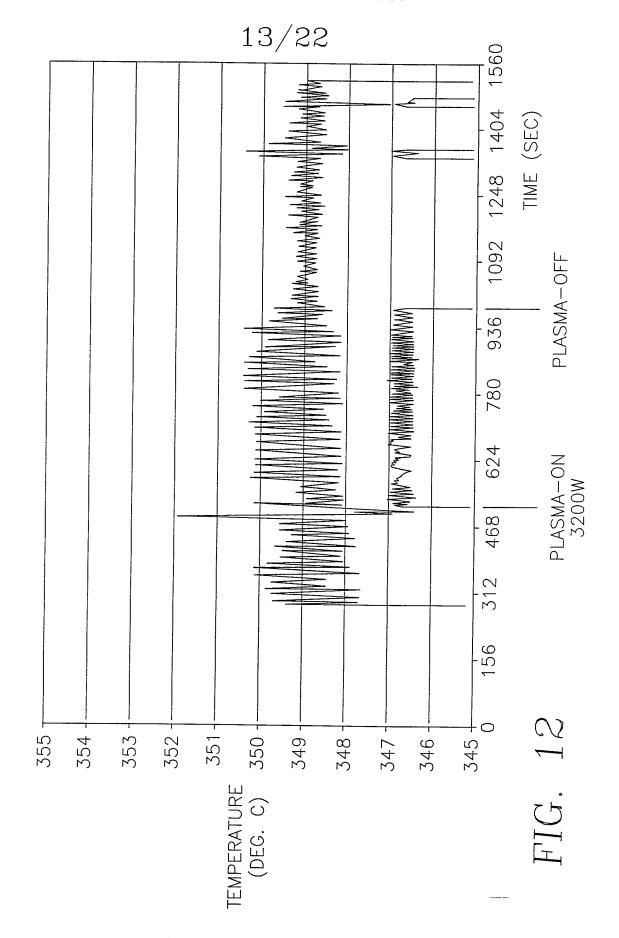


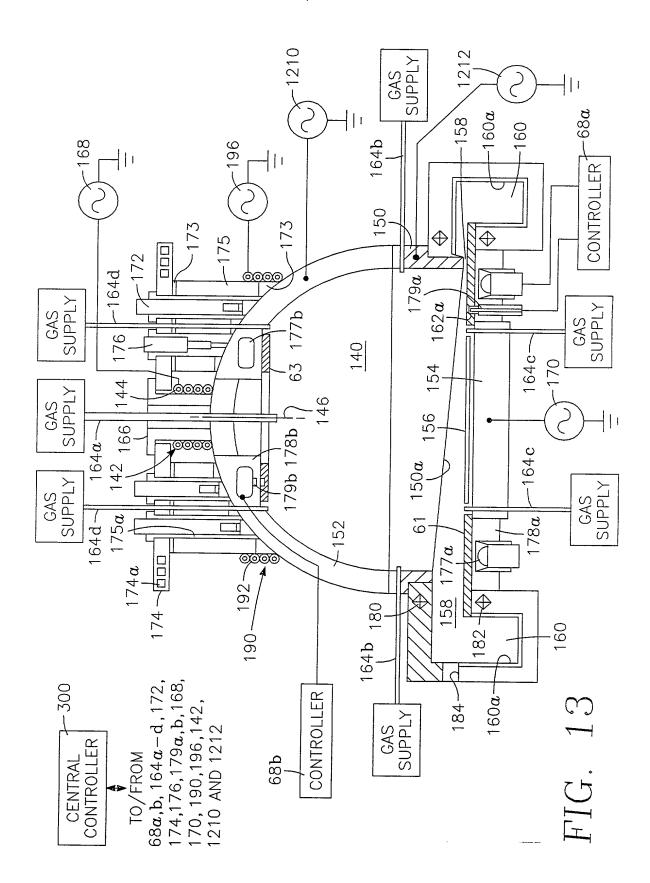




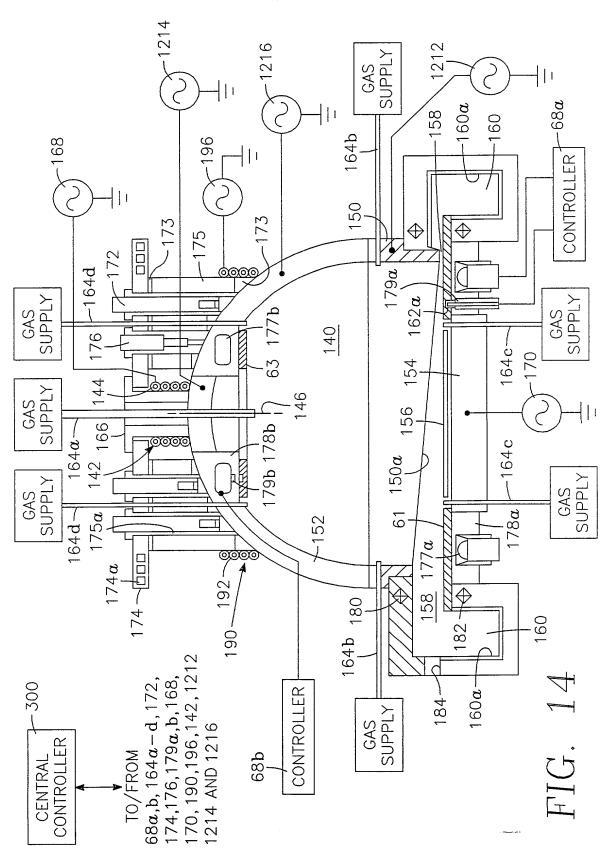


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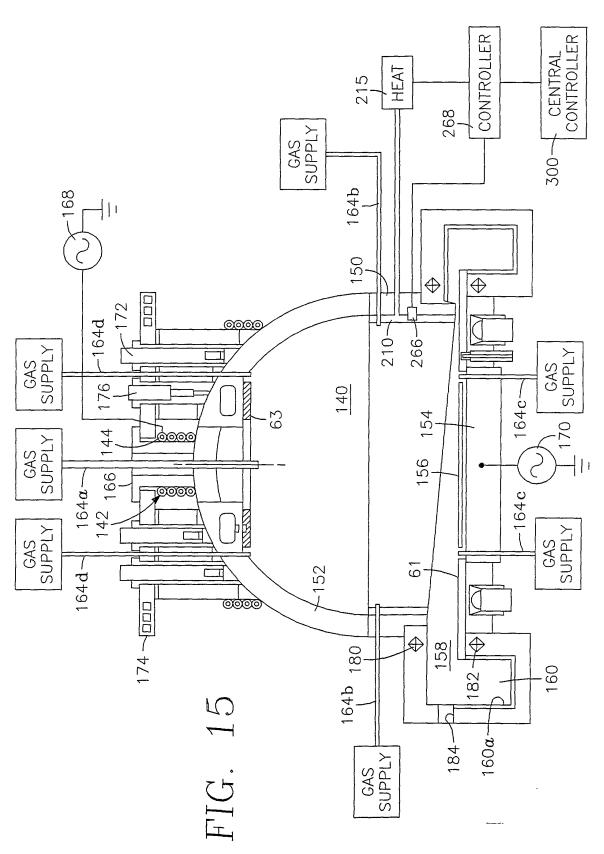


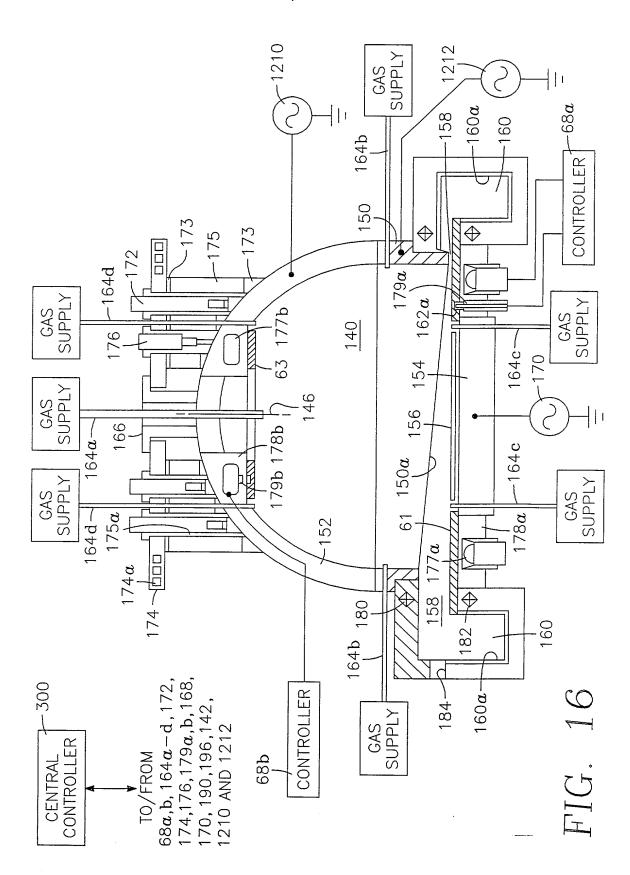


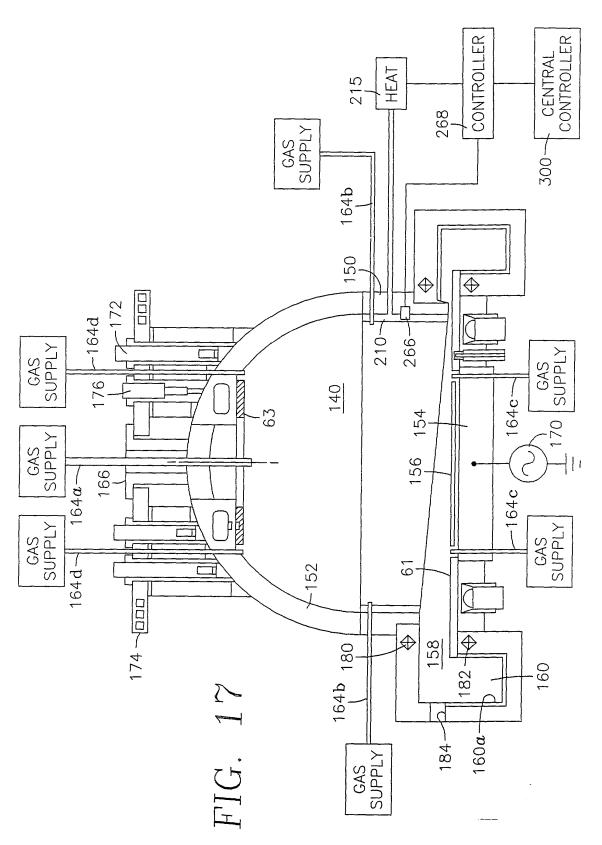




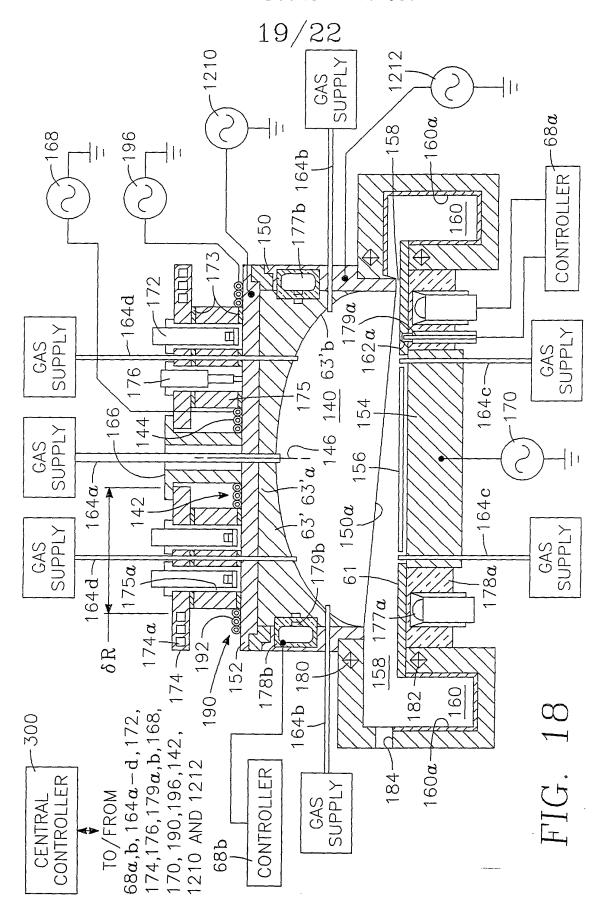
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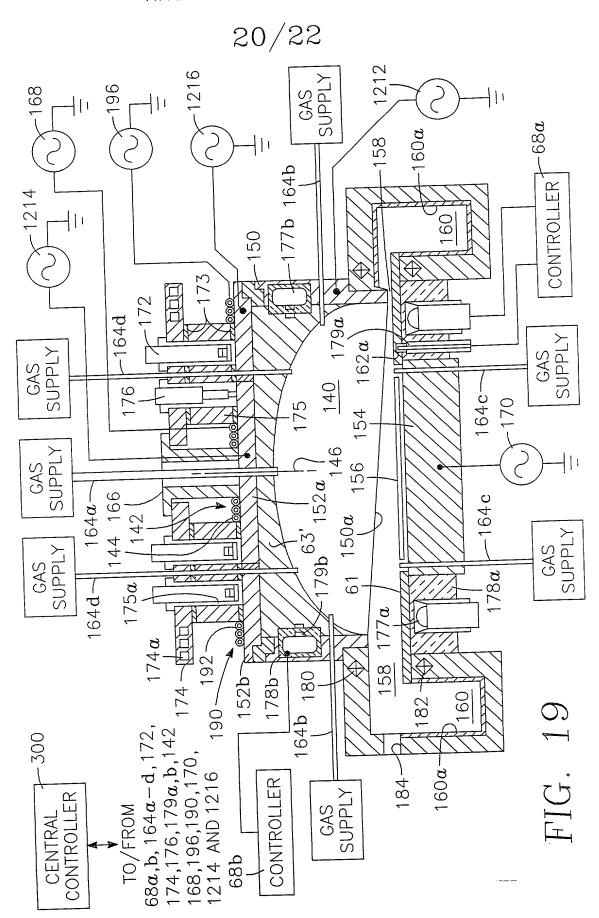






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